



Road to Chiplets: Architecture

July 13 & 14, 2021

Making Chiplet-based Systems Reliable: Approaches to Support Heterogeneous Integration

Abhijit Dasgupta

Center for Advanced Life Cycle Engineering (CALCE)

University of Maryland, College Park, MD 20742

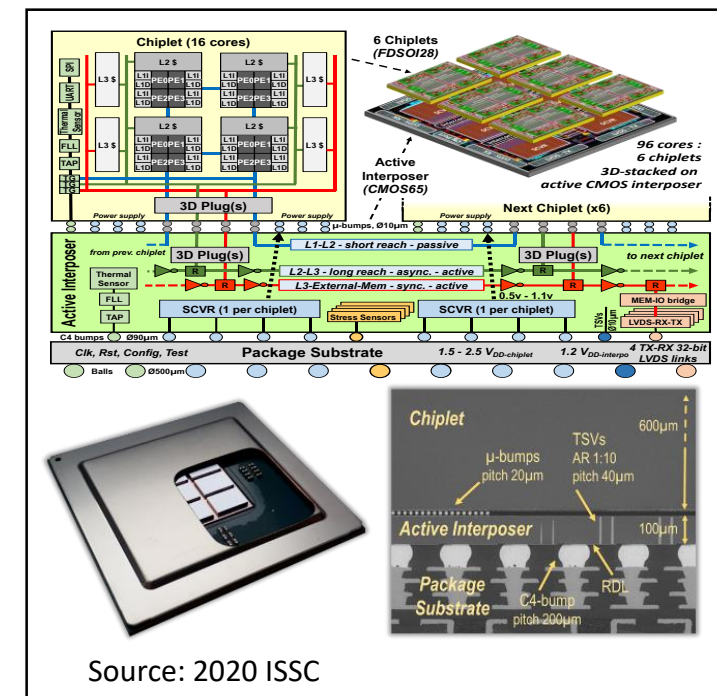
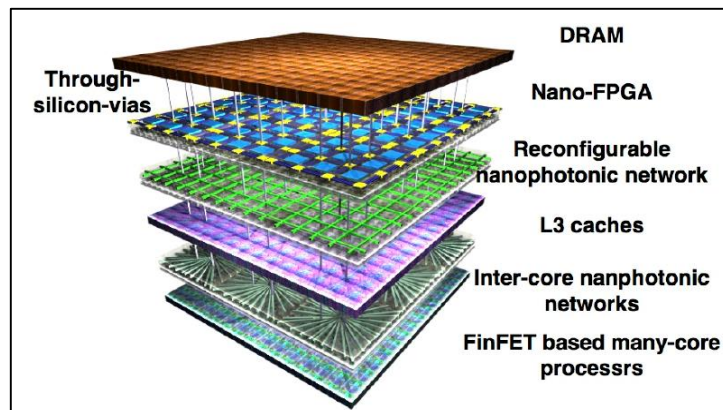
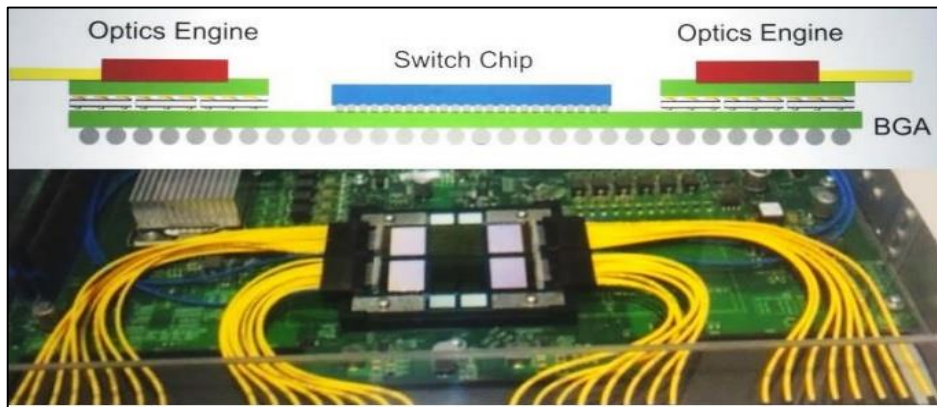
dasgupta@umd.edu

Acknowledgment:

Richard Rao (Marvell Corporation), Shubhada Sahasrabudhe (Intel)

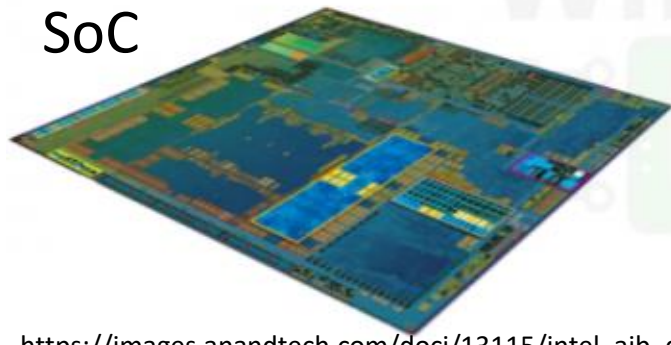
Chipselets are a critical building block in heterogenous integration:

- ❑ Electronic (Passive/Active)/photonic/MEMS/Sensor devices
- ❑ Digital; Analog; Logic; Memory; Power; RF
- ❑ System, Package (Chipselets) and Wafer levels, including Interconnects and Substrates
- ❑ 2.5D and 3D Packaging technologies

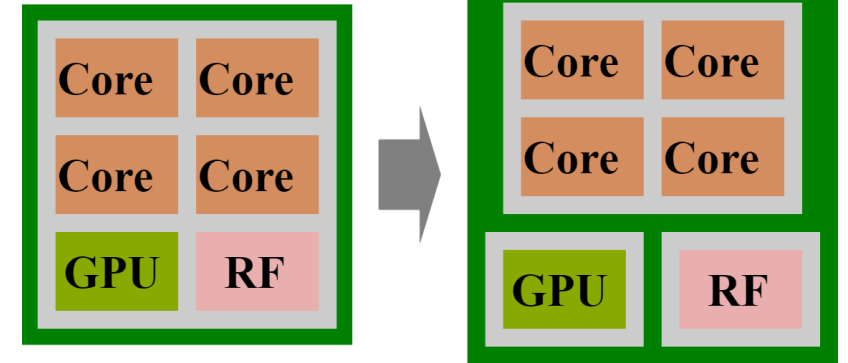
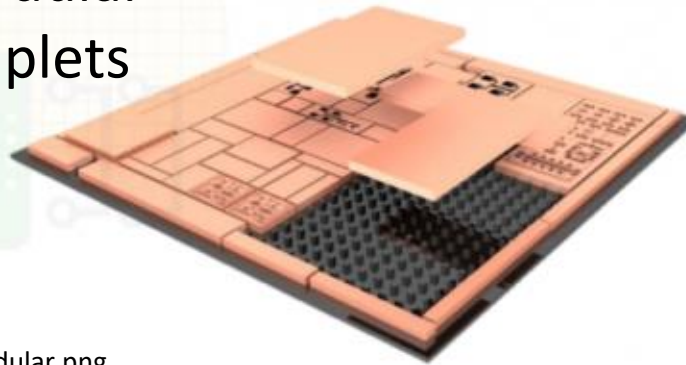


Chiplet architectures bring unique reliability issues

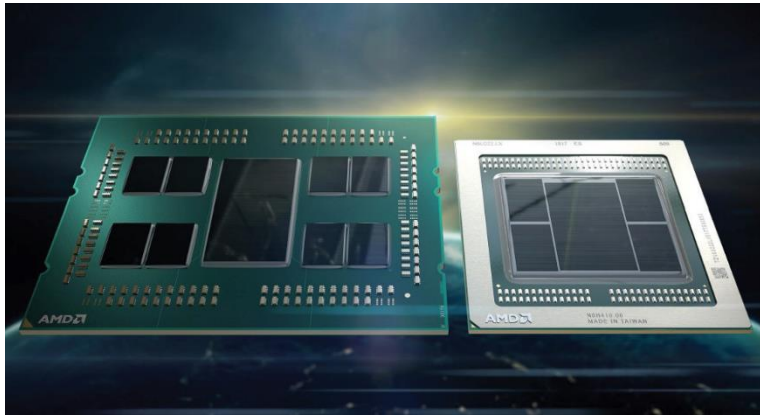
Monolithic
SoC



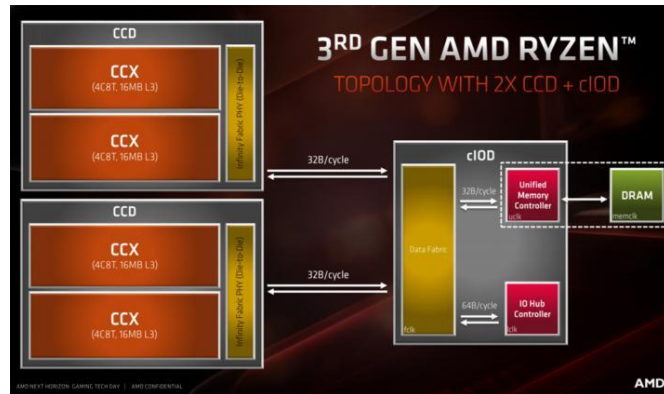
Modular
Chiplets



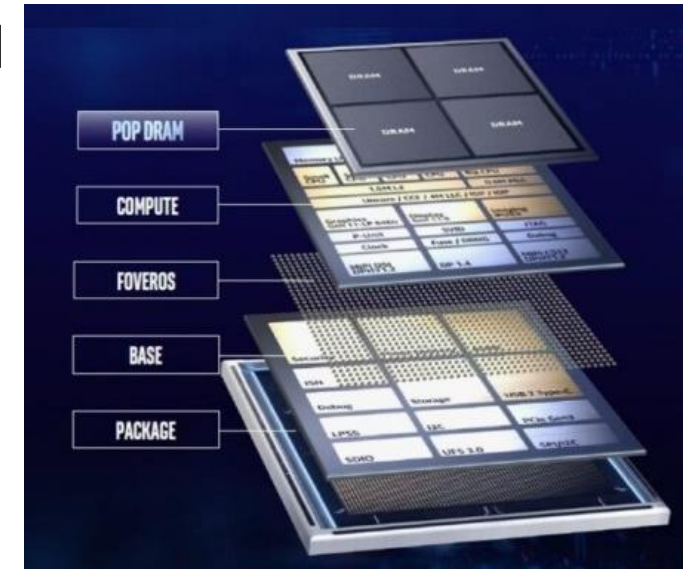
https://images.anandtech.com/doci/13115/intel_aib_darpa_modular.png



AMD



Intel

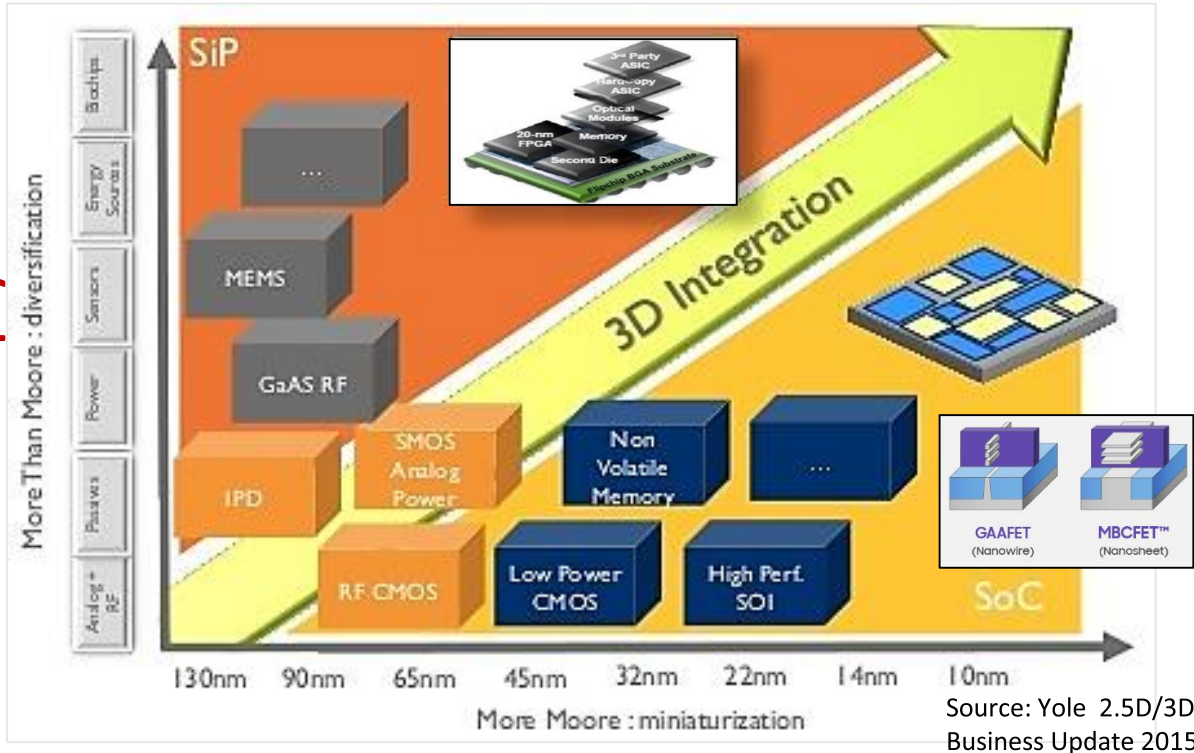


<https://www.hardwaretimes.com/difference-between-intel-and-amd-ryzen-processors-chiplet-vs-monolithic/>

Chiplet-Based Systems: Convergence of Semiconductor & Packaging (Disaggregation and Re-aggregation)

Approach for reliable chiplet architectures

Multi-physics



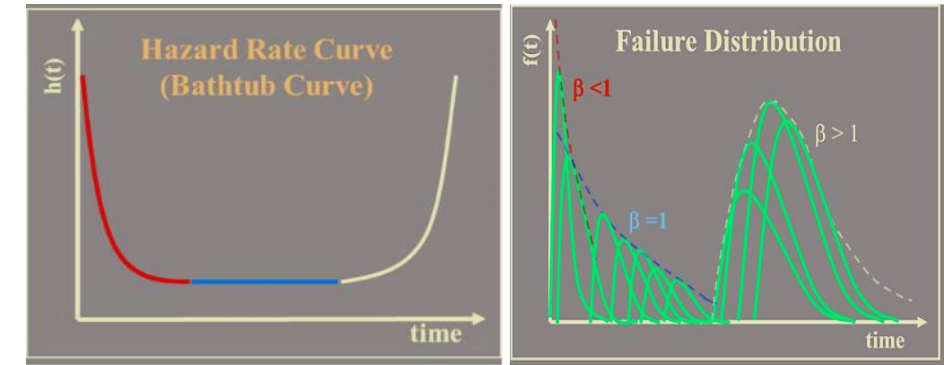
Multi-scale

Convergence of Semiconductor and Packaging Industries

Heterogeneous chiplets:

- **technology** (IC-node, photonics, MEMS, sensors)
- **circuit type** (DRAM, Serdes and logic, photonics, power, RF)
- **packaging** (substrate, interposer and interconnect method)

Reliability Assurance Activities



Reliability
Targets

Life Cycle
Conditions

Design for
Reliability

Manufacturing
for Reliability

Knowledge
based Testing for
Qualification

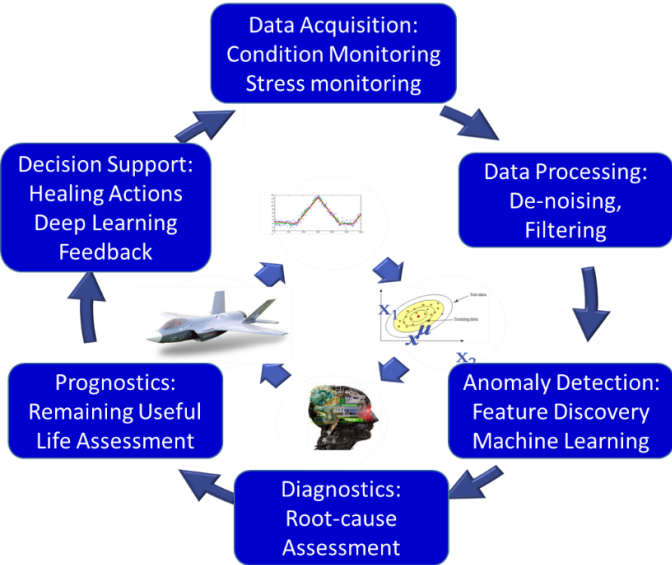
Product Health
Management

Supply chain
Integration

Reliability of **multi-physics/multi-scale** HI systems requires holistic cradle-to-grave methodology

Chiplet reliability

Prognostics and Health Management



Degradation and Failure Mechanisms

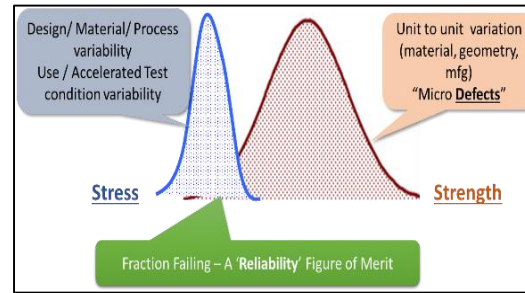
Overstress Mechanisms

Mechanical	Yield, Fracture, Interfacial de-adhesion
Thermal	Glass transition (T_g) Phase transition
Electrical	Dielectric breakdown, Electrical overstress, Electrostatic discharge, Second breakdown
Radiation	Single event upset
Chemical	-

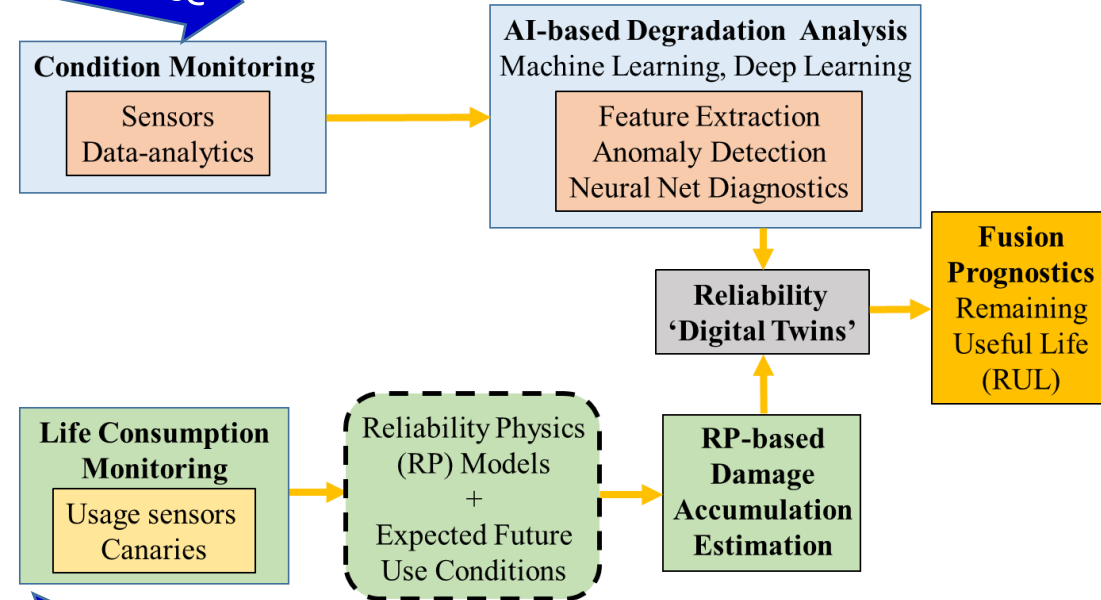
Wearout Mechanisms

Mechanical	Fatigue, Creep, wear
Thermal	Stress driven diffusion voiding (SDDV)
Electrical	TDDB, Electromigration, Surface charge spreading, Hot electrons, CFF, Slow trapping
Radiation	Radiation embrittlement, Charge trapping in oxides
Chemical	Corrosion, ECM Dendrites & whiskers, Depolymerization, Intermetallic Growth,

Machine Learning & Artificial Intelligence



Fusion of bottom-up physics and top-down AI approaches

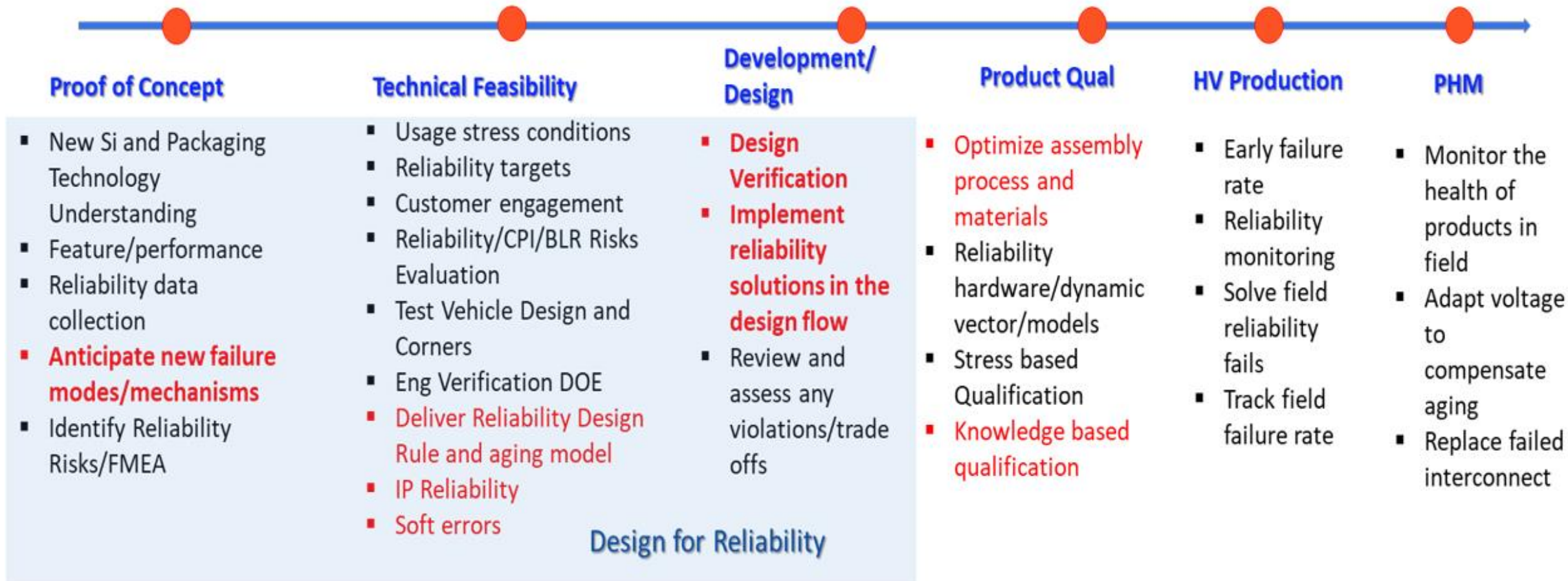


Reliability Physics



HETEROGENEOUS
INTEGRATION ROADMAP

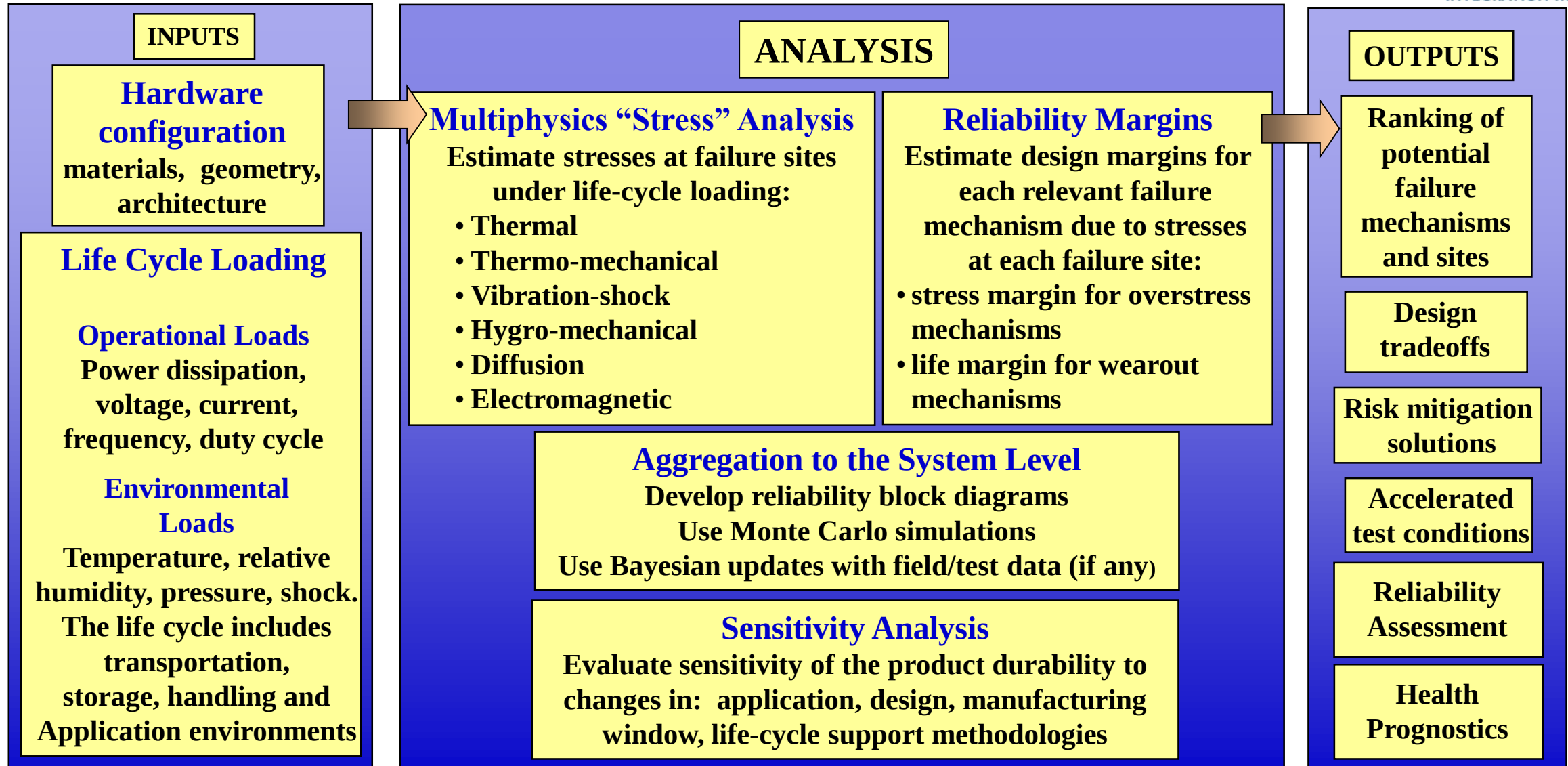
Reliability Functions in Product Lifecycle



Designing for reliability: Reliability-physics process

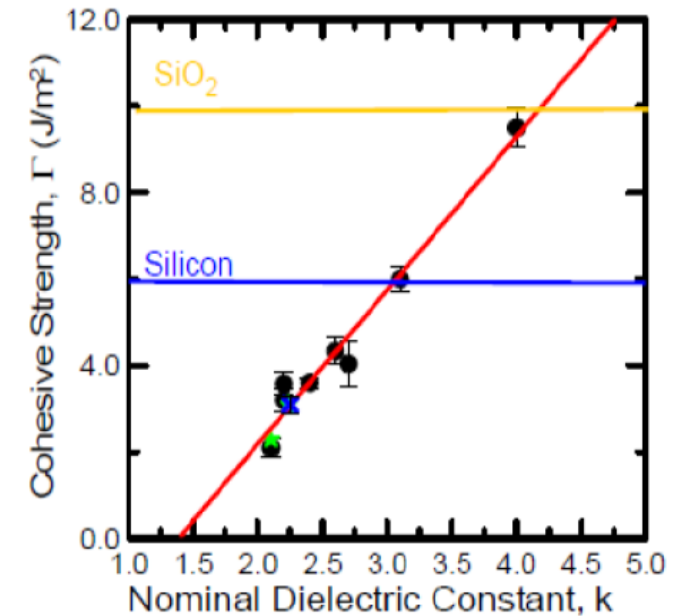
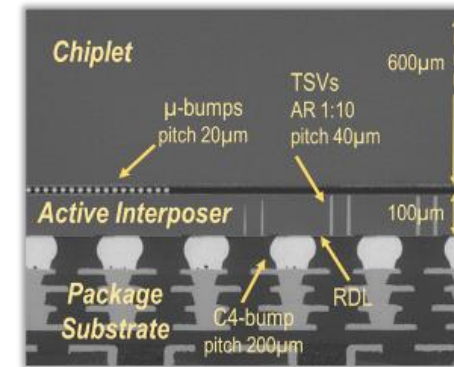
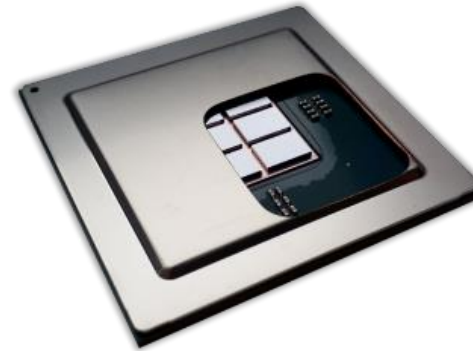
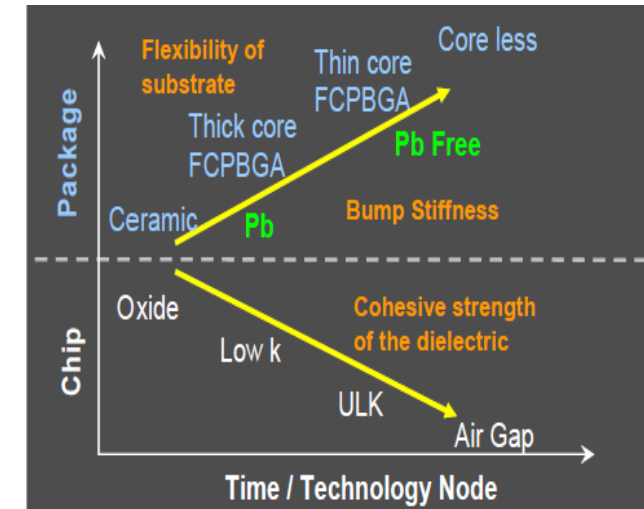


HETEROGENEOUS
INTEGRATION ROADMAP



Advanced chiplets: CPI challenges

- ❑ CPI issues are increasing with newer Si nodes
 - ❑ Device and packaging reliability were treated separately in old nodes
 - ❑ Advanced Si with low k, CPI requires co-development of device and package
- ❑ Low k and Ultra low k introduction
 - ❑ Fragile and poor adhesion
- ❑ Build up substrate
 - ❑ High CTE and warpage
- ❑ Pb free or Cu pillar interconnect
 - ❑ Higher modulus
- ❑ Complex die
 - ❑ Big die size
 - ❑ Higher power
- ❑ Bump on trace
- ❑ More advanced packaging induced board-chip-package interaction
 - ❑ WLP
 - ❑ 2.5D/3D
 - ❑ Big FCBGA



Chipselets: An overview of 3D IC stresses and reliability

Impact of Flip Chip Package on 3D chip-stack (CPI)

- Stress induced by Cu-pillars on low-K
- Stress induced by overmold, laminates CTE mismatch
- ...

Impact of TSV/uBump on top die

- Built-in stress
- Stress varies as function of temperature

Impact of 3D-SIC bonding on dies

- Stress during bonding
- Stress due to underfill CTE mismatch
- ...

Microbumps:

- Material anisotropy
- Length-scale effects

Impact of die thinning

- Releases stress
- Strength of die
- ...

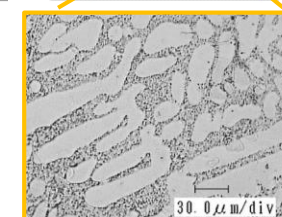
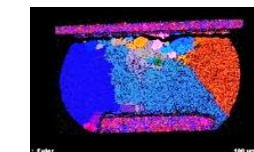
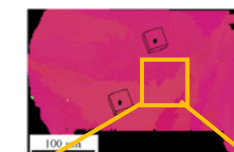
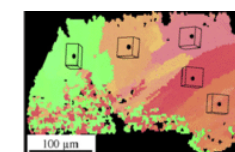
Impact of TSV on bottom die

- Built-in stress
- Stress varies as function of temperature
- ...

Stress/strain can lead to

- mechanical failures due to delamination, peel, fatigue, ...
- electrical impact due to parameter shifts, increased variability, EM, ...

Multi-scale



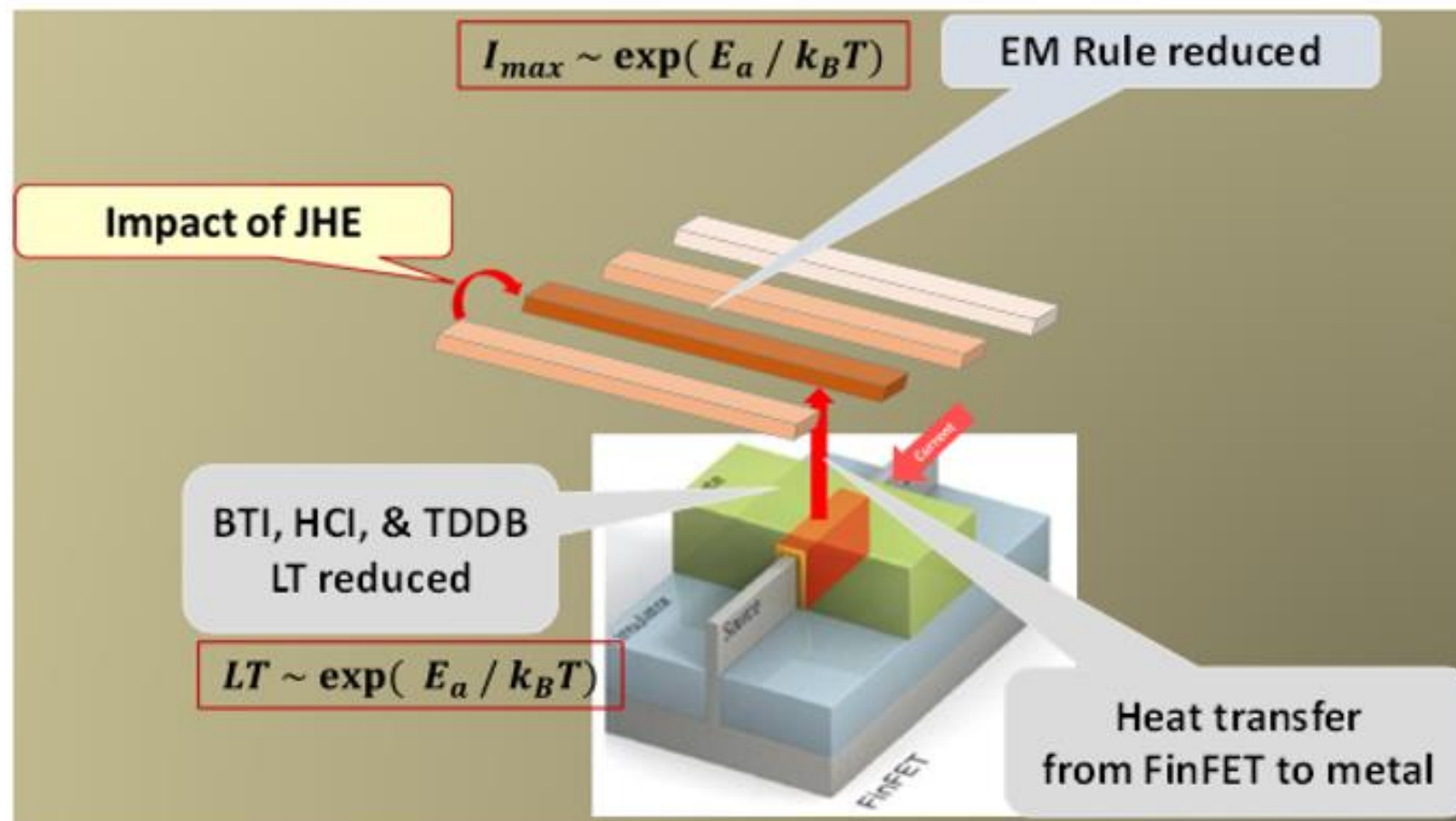
SHE-induced FEOL failure modes

Electromigration

Bias Temperature
Instability

Hot carrier Injection

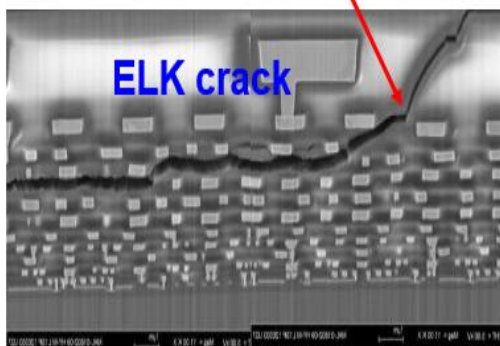
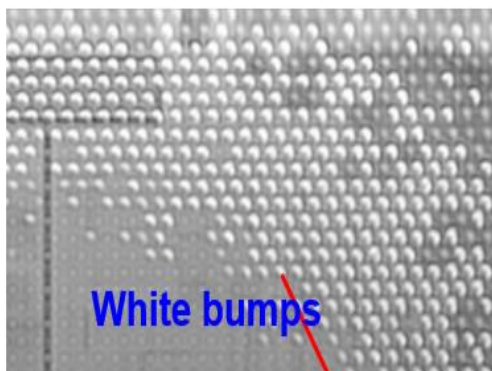
Time-Dependent
Dielectric
Breakdown



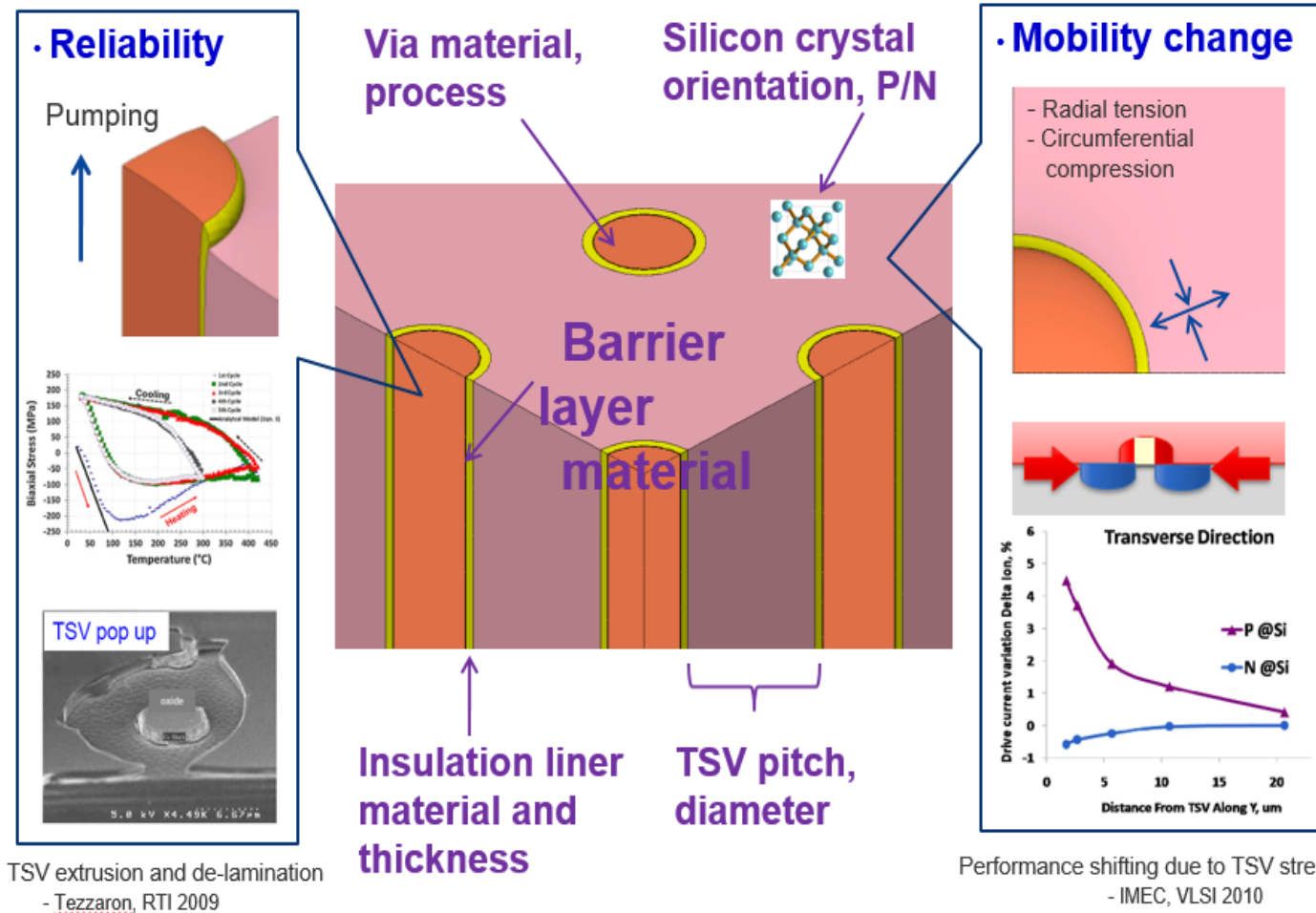
Typical CPI-induced MEOL/BEOL failure modes



HETEROGENEOUS
INTEGRATION ROADMAP

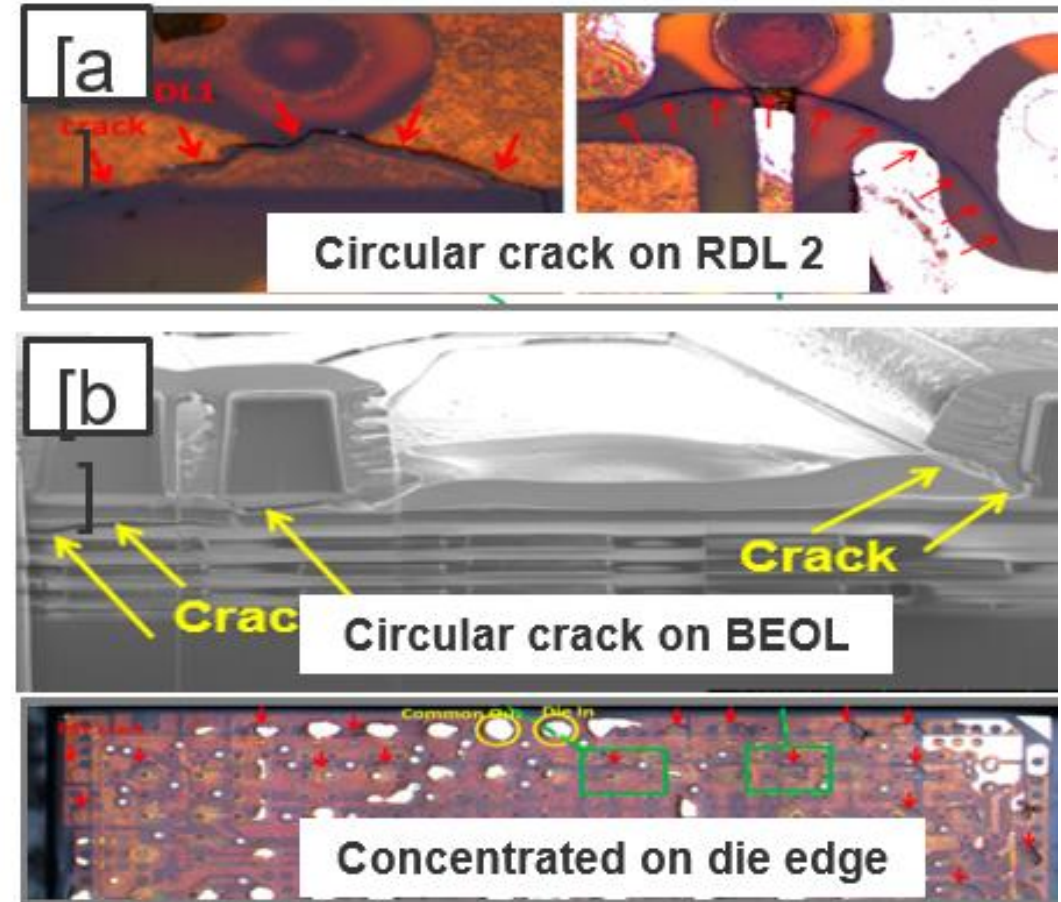
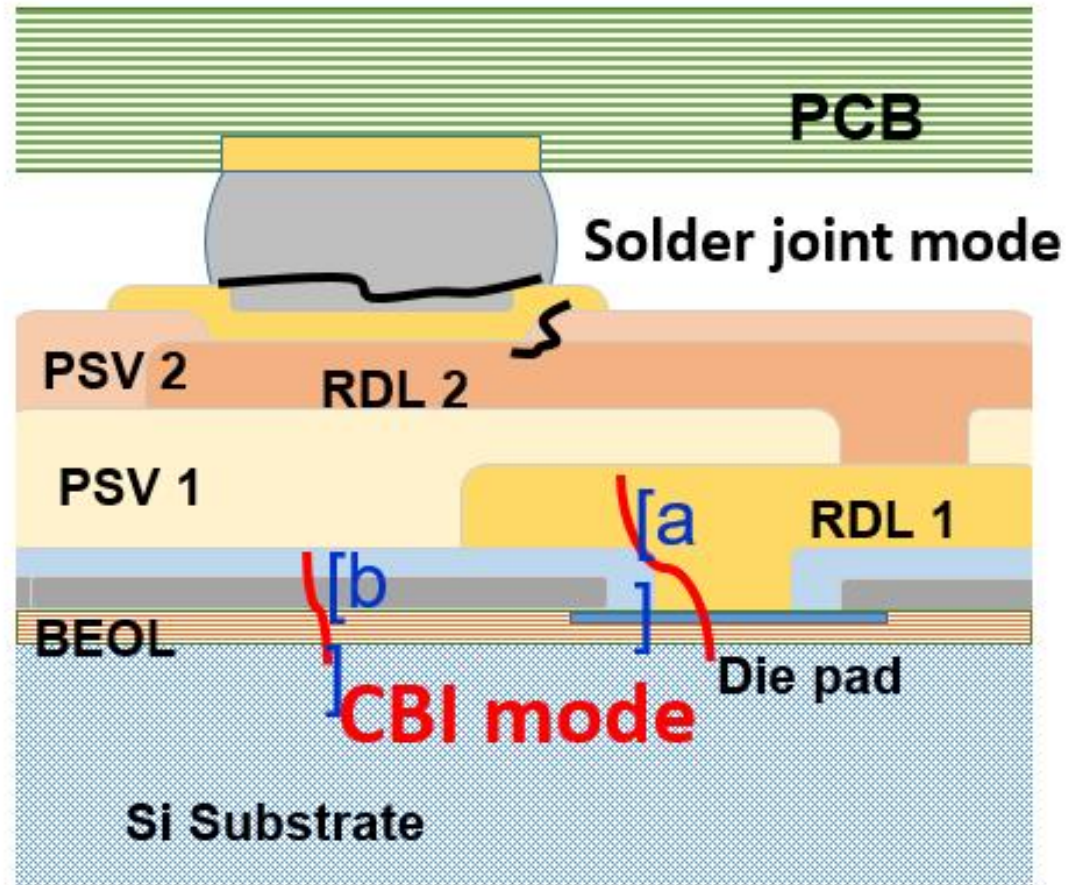


Source: IBM



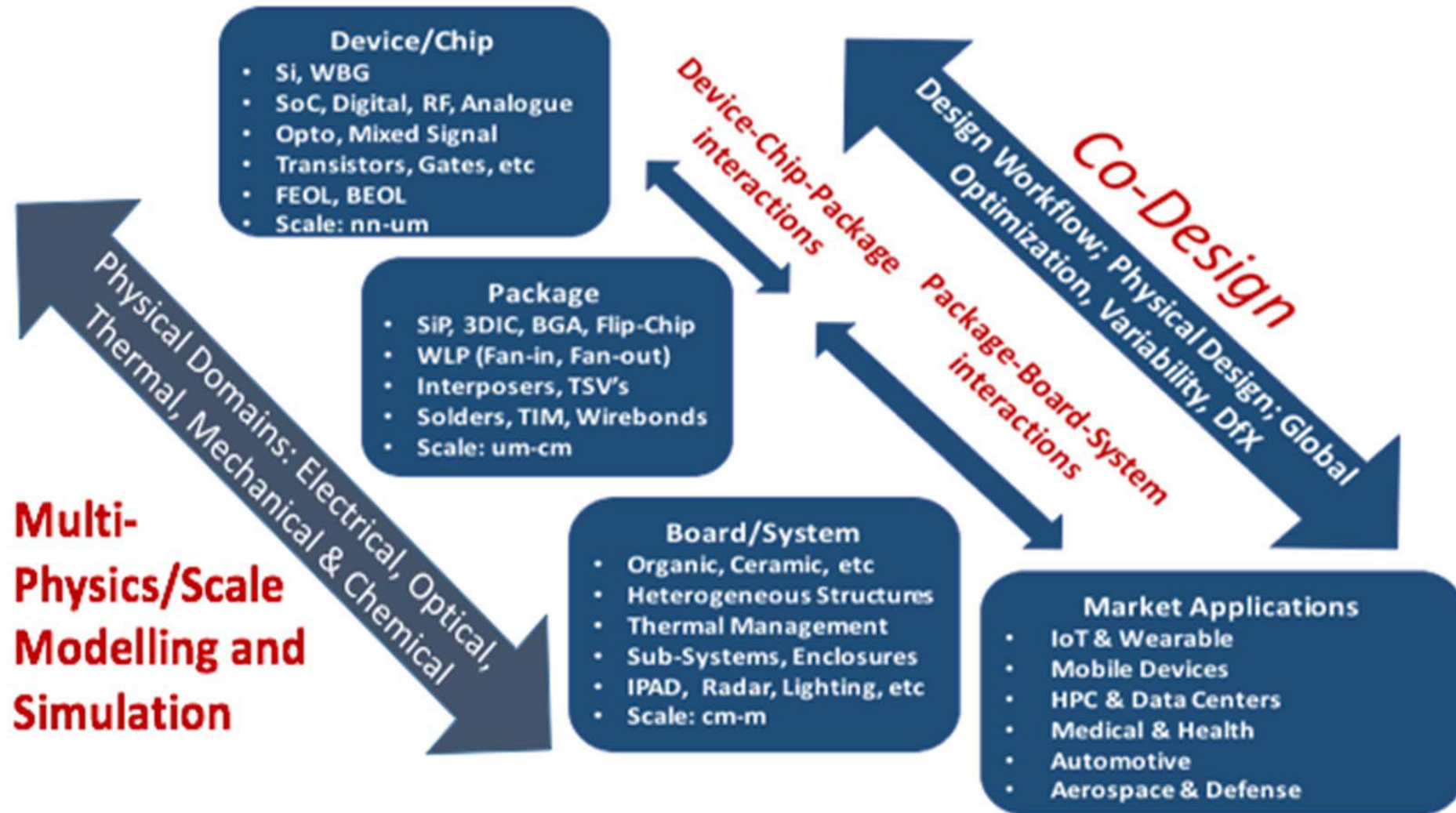
Source: Synopsys

CBPI-induced failure modes



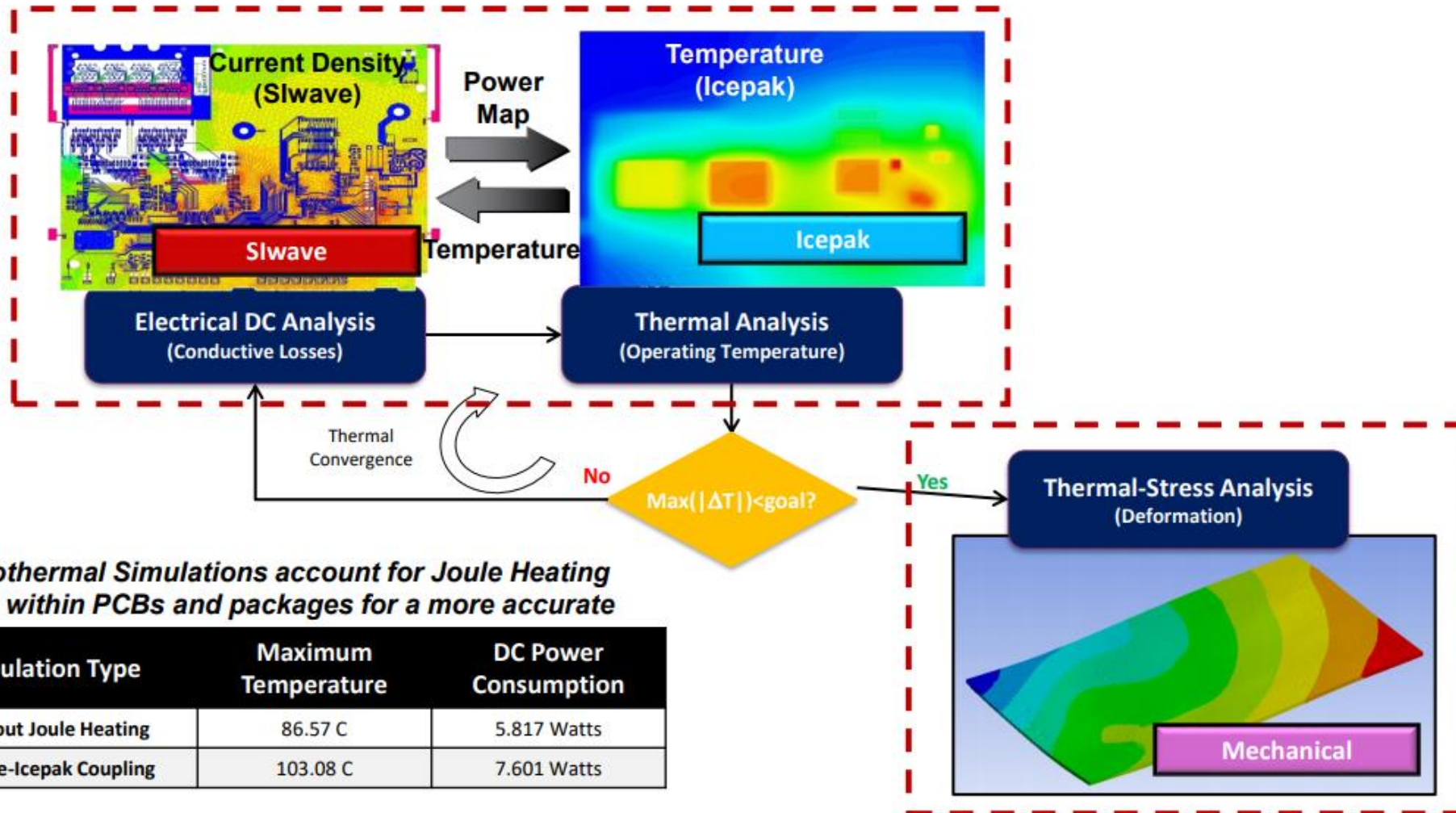
Mediatek, 2017 IRPS

Chipselets: Physics-based modeling simulation and co-design



Source: HIR; Modelling and Simulation TWG

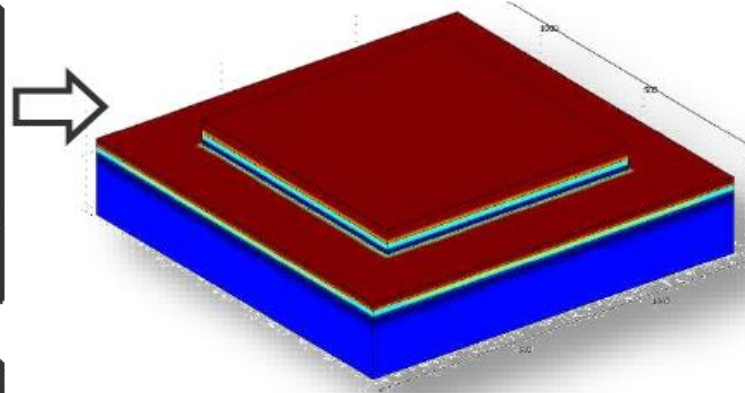
System-level multiphysics simulations



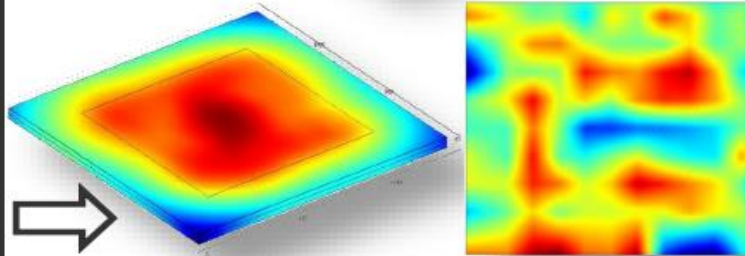
Source: ANSYS

Multi-scale and multi-physics CPI flow

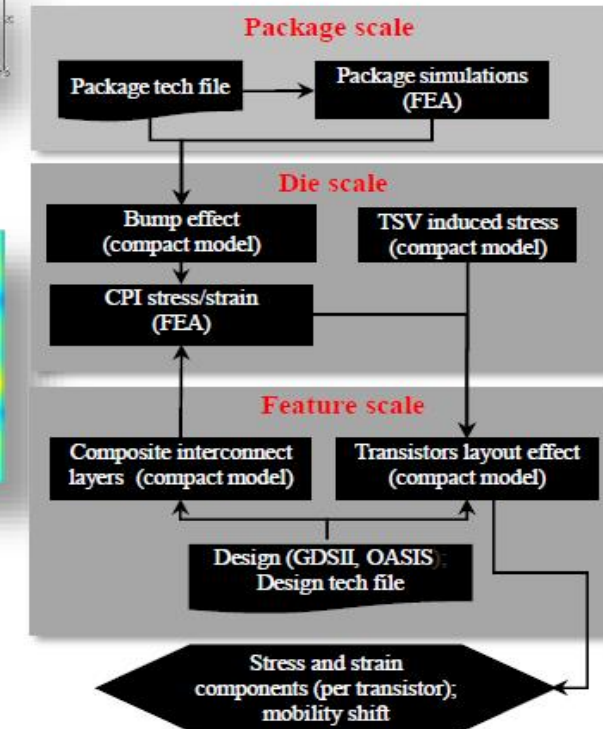
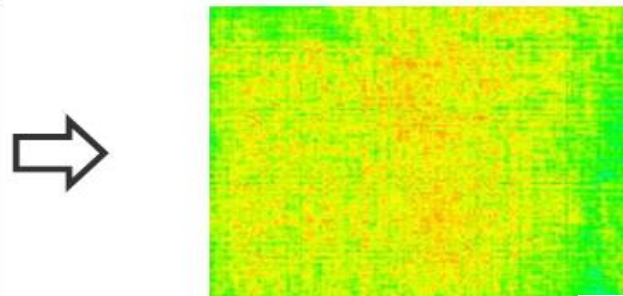
Package-scale simulation (FEA)
Input: geometry; material properties; smeared mechanical properties for RDLs, Silicon/TSV bulk, interconnect.
Output: field of displacement components on the die faces.



Die-scale simulation (FEA)
Input: geometry; field of displacements on the die faces; coordinate-dependent mechanical properties for RDLs, Silicon/TSV bulk, interconnect.
Output: Distribution of the strain components across device layer.



Layout-scale w/feature-scale resolution (compact model):
Input: GDS; distribution of the strain components across device layer.
Output: Transistor-to-transistor variation in stress components



Source: Mentor Graphics

Modes/Mechanisms/Models for Degradation & Failure



HETEROGENEOUS
INTEGRATION ROADMAP

Electrical Thermal Moisture Thermo-mechanical Mechanical DfR Methods MfR Methods

Multiphysics

Devices

Multiscale

Interconnects

Packaging/
System

Module/System

Multiscale Integration	Multi Physics	Electrical Stress		SI/PI (Electrical Performance)	Thermal Analysis	Moisture	Thermal Mechanical Stress		Mechanical Stress		Thermal Interaction with SI/PI	Stress Interaction with SI/PI	Simulation/Modeling and Co-Design Flows		Design Flows	Manufacturing Variability	Material Property and Variability	
		Failure Modes	Failure Mechanism and Reliability Models			Failure Modes	Failure Mechanism and Reliability Models	Failure Modes	Failure Mechanism and Reliability Models	Failure Modes	Failure Mechanism and Reliability Models			Failure Modes	EDA Flows	PDK/ADK		
Devices	Transistor	FinFET and GAA	Leakage current, ripple currents, unlabeled performance and ESD	N/PBTI models with recovery; HCI model; TDDB Weibull model; Oxide & junction breakdown model	Transistor SPICE	FinFET SHE	No known failures	None	FinFET SHE channel stress; ubump/CA bump/TSV; system level stresses	FinFET SHE Models; CPI Model; Piezo-electrical models	No known failures	None	SHE effect on SPICE parameters	Influence of Si stress on SPICE parameters	Effects of degradation mechanisms and process variabilities on electrical functionality	Cadence; Relaport; Mentor Graphics	Integrate degradation models into Device SPICE Model	
	Interconnects	MEOL/BEOL Metal/Via /ELK	Electromigration; Inter Layer Dielectric ELK Breakdown; MEOL Oxide Breakdown; EOS	Electromigration model; Dielectric breakdown model	Extraction of RLC Model	Joule Heating simulation; SHE effects on MEOL/BEOL	Pad and underline metal corrosion; Cu/ELK delamination & Cu loss/diffusion	Electrochemical corrosion; Interface degradation due to moisture absorption; Barrier metal oxidation	SHE failure in Cu/ELK, MEOL, BEOL, ubump, TSV; RDL failures from package stress, Cu fatigue; LowK/ELK layer cracking & delamination	Creep induced voiding; CTE mismatch; SHE induced localized thermal cycling	LowK/ELK layer cracking & delamination	Fatigue by bending	Joule/SHE temp effects on RLC	Effect of Cu/ELK stress on RLC	CPI induced Cu/ELK cracking; SHE/SHE stresses; stress from bumps/TSV/RDL & Packaging	Ansys Mentor		
		RDL/UBM RDL/Dielectric	Electromigration	Extraction of RDL RLC Model	BEOL Joule/SHE effect on RDL temperature	Cu dendrite	Electro-chemical corrosion	RDL cracking	ubump/TSV/ Package/ Board effects on RDL stress			Effect of RDL temp on electrical model	Effect of RDL stress on electrical model	CPI/CBP induced failures; RDL cracking & delamination	Effect of temp and stress on RDL EM			
		Au/Cu Wirebonding	Electromigration			IMC Corrosion		Bond wire fatigue		Cu/ELK cracking	Bonding force models							
		ubump/CA Bump/UBM	Electromigration induced voids	Black's model; Multiphysics EM model including electron, thermal gradient, stress gradient and atomic diffusion	ubump electrical model	Die Internal Joule/SHE temp effect & external temp effect on bump temperature	UBM delamination	Bump joint cracking; Under bump ELK cracking; Under pad cracking in substrate	CTE mismatch induced stress; Fatigue	Tensile stress causes bump peel; cracks at die attach, dielectric layer, interposer, UBM, solder joints	Fracture/fatigue from shock, drop, impact, Vibration, e.g. in die attach, dielectric layer, interposer, UBM, solder joints	Effect of temp on bump electrical model	Effect of bump stress on electrical model	Multi Physics Bump EM - local current, temp, temp gradient and stress effect on ubump EM	Bump fatigue: effect of local temp & stress on fatigue life			
		TSV/Interposer/EMIB	Electromigration; Barrier Dielectric breakdown	Black's model; Multiphysics EM model including electron, thermal gradient, stress gradient and atomic diffusion	TSV electrical model	Internal Joule/SHE temp effect on the TSV temp; External temp effect on TSV temp.		Cu pumping/TSV pop up	Cu extrusion due to CTE mismatch with Si; plastic reflowing at high temp			Effect of TSV temp on electrical model	Effect of TSV stress on electrical model	TSV EM response to local current, temp field and stress; TSV Pop out and stress effect TSV barrier BD?	Barrier breakdown - How does voltage/current, temp and stress effect TSV barrier BD?	Package material thermal/mechanical properties; Die metal stack and thermal/mech properties; ubump/CA bump/TSV thermal mechanical		
Packaging / System	Passivation	Passivation cracking	EOS induced cracking			Passivation cracking & delamination; underfill/Mold compound delamination		Passivation cracking	CPI stress in SiN						propagates; Cu/Cu fracture criteria; Void initiation and propagation criteria; Interconnect fatigue/creep model;			
	Underfill					Underfill to die/substrate delamination; underfill swelling	Moisture degradation in underfill & at interfaces	Bump joint cracking	Solder joint fracture and fatigue due to underfill expansion						Package interface fracture criteria; Moisture diffusion and vapor pressure model; IMC			
	High Density Substrate	Metal trace electromigration	Package Substrate RLC model extraction	Co-thermal sim from die to package	Metal trace corrosion		Metal trace/via cracking			Thermal - electrical performance interactions	Mechanical - electrical performance interactions	Cu trace EM - effect of local current, temp and stress	Thermal & mechanical effect on Cu trace/via cracking	thermal/mech/electrical properties; Photonics optical properties				
	Wafer Level Package							Warpage										
	Fanout Package							Warpage										
	2.x/2.5D Interposer Package (CuW5 and EMIB, etc)						Warpage; Embedded die delamination from substrate & sidewall; pole & ubump cracking & delamination; Solder/TIM delamination											
Module/System	3D Package (Foveros, etc)			Mold compound pop-corn; Anisotropic conductive adhesive cracks				FinFET Ion shift (due to TSV/Si CTE mismatch, ubump stress, shrinkage of underfill & EMC); TSV effects on BTU/HQ; BEOL cracking; Cu pillar joint failure; Mold compound pop-corn; conductive adhesive cracking										
	Chiplet/ROG	ESD						Die edge cracking; Under bump ELK cracking										
Module/System	Printed Circuit Board Assembly		Leakage current and shorts from Conductive filament formation	electro-chemical metal migration	PCB Board electrical model	Co-thermal sim from die to package to system	Leakage current and shorts from loss of surface insulation resistance & conductive filament formation	moisture ingress, leading to fiber-matrix debonding and electro-chemical metal migration	Solder joint cracking; Cracking of PTH plating; PCB delamination; trace cracking; Warpage	thermomechanical fatigue of trace and solder, IMC fracture; CTE mismatches between component / PWB, metallization/ dielectrics	Solder joint cracking; pad cracking	Stress exceeds the material and interface strength	Effects of PCB temp and corrosion on electrical model?	Effects of PCB stress on electrical model?	Board level Solder joint Reliability	ANSYS Mechanical	PCB thermal/ mechanical properties; Solder joint fatigue/creep model; Solder joint dynamic properties	

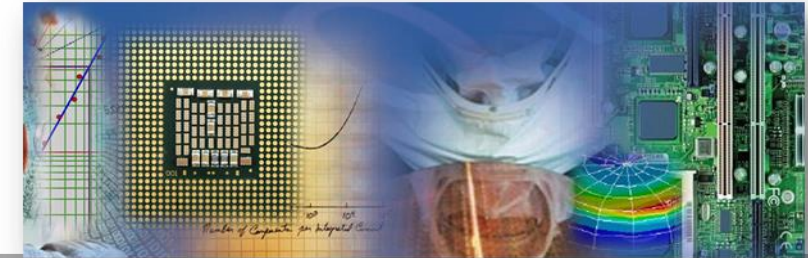
Chiplet reliability assessment capabilities: status

Key Elements for DfR Flow	Wafer Level DfR	Package and System Level DfR	Chip to Package to Board Interactions
Electrical and Thermal Stress	Localized Self Heating and hot spots	Global Level thermal managements	FEOL/BEOL and systeme level thermal interactions
Failure Modes	TDDDB, HCI, BTI , EM and SM, etc	Warpage, delamination; C4, ubump, DBI, TSV, Optical Via interconnect fatigue and migration failure, etc	Global and local Stress effects on Cu/ELK failure, stress effects on FET's mobility
Failure Mechanism and Reliability Model	Weibull, Lognormal, Power Law Model, Aging Model, etc	Weibull, Lognormal, multiphysics models, etc; many are under development	Under development
Material Chaterization and Modeling	Modeling device thermal characteristics (Thermal resistance) Modeling device aging Modeling the impact of stress on device threshold, delay, etc.	To make materials data useable by EDA tools – and enable them to produce accurate and meaningful results – materials data needs to be presented in a machine-readable format and agreed upon with EDA tool vendor.	Modelling multi scale and multi physics failures
Process Design Kit (PDK)	Foundry Design Kit	Assembly Process Design Kit	Under development
EDA Flow	Cadence Spectre/HSPICE, etc	Ansys/Mentor, etc	Mentor/Synopsys
Circuit/System Reliability	HCI/BTI and EM Available; TDDDB and SM not Available	Under development	Under development
Established			
Partially Established			
Under development or Not Available			

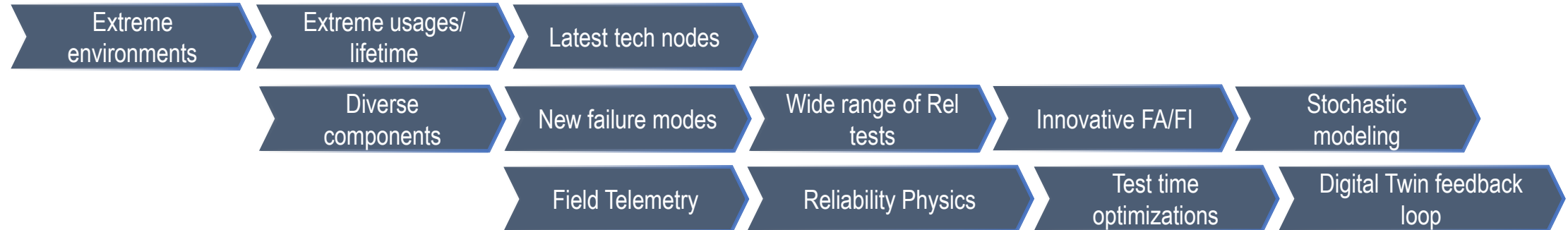
Qualification and testing: Reliability validation/verification



The changing and challenging landscape



Need for dynamic, flexible models and methods



Multi-physics methods to quantify 'stress' and 'strength' distributions at potential sites of failure

Qualification testing needs to be Customized, Knowledge-based and Innovative

Data feedback loop with Digital Twins to validate failure characteristics and run virtual experiments

Integrated PHM - Self-cognizant, intelligent, bio-mimetic hardware to 'age with grace'

Source: Sahasrabudhe (Intel)

Summary: Reliable Chiplets and HI Systems

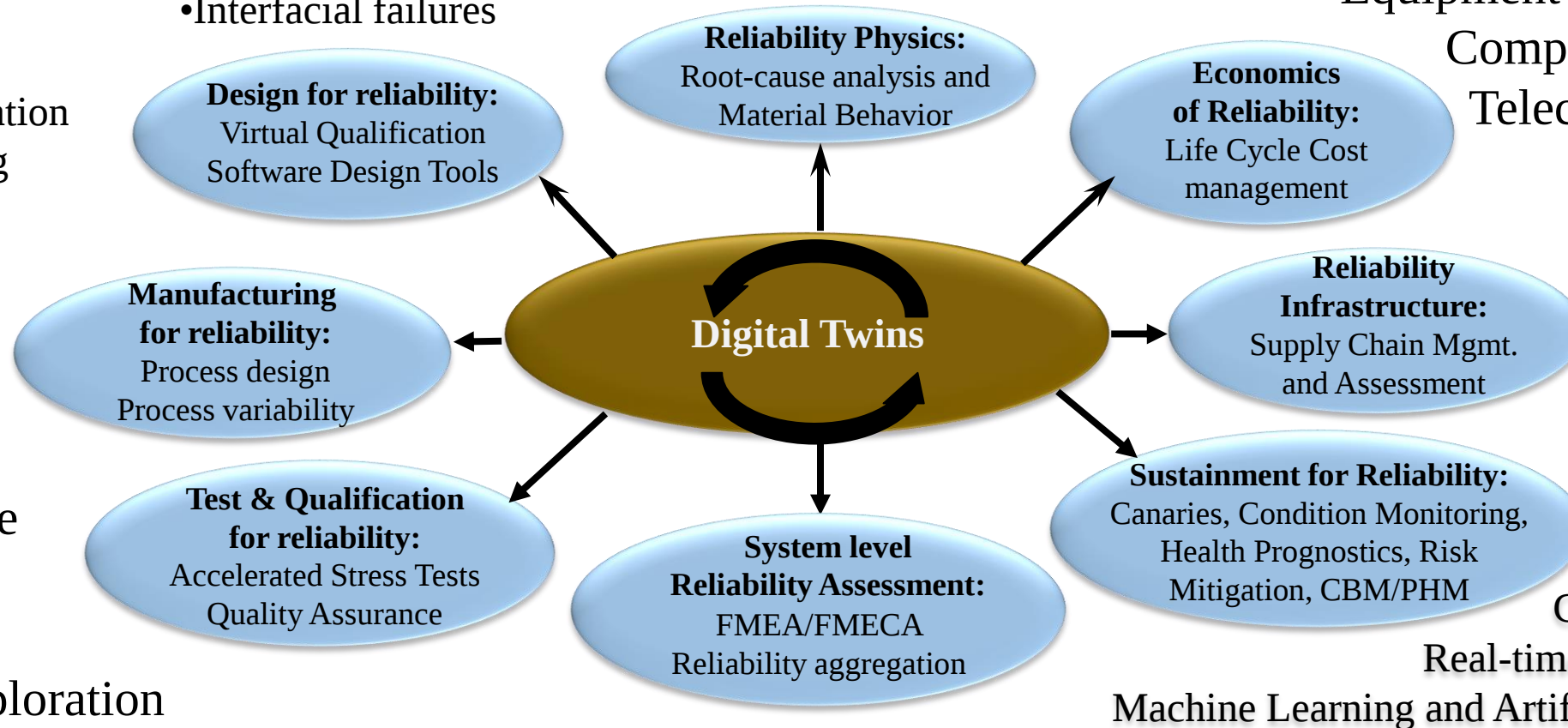
Convergence of Reliability-Physics (RP) and Artificial Intelligence (AI)

- Fatigue and Fracture
- Plasticity, creep
- TDDDB
- ESD/EOS
- Electromigration
- Wear/fretting

- Whiskers
- Aging of polymers
- Interfacial failures

- Corrosion
- ECM

Semiconductor and Packaging
Equipment Manufacturers
Computer/Consumer
Telecommunication
Medical



Aerospace
Automotive
Defense
Industrial
Energy exploration

IoT
Cloud Computing
Real-time Data Analytics
Machine Learning and Artificial Intelligence

Intelligent, resilient, self-cognizant, self-healing chiplet-based HI systems

Thank you sponsors!

ADVANTEST®



SYNOPSYS®



Global Companies Rate Advantest THE BEST ATE Company 2021



Advantest receives highest ratings from customers in annual VLSIresearch Customer Satisfaction Survey for 2 consecutive years.

Global customers name Advantest THE BEST supplier of test equipment in 2020 and 2021, with highest ratings in categories of:

**Technical Leadership – Partnership – Trust
– Recommended Supplier – Field Service**

“Year-after-year the company has delivered on its promise of technological excellence and it remains clear that Advantest keeps their customers’ successes central to their strategy. Congratulations on celebrating 33 years of recognition for outstanding customer satisfaction.”

— **Risto Puhakka**, President VLSIresearch

Amkor's Differentiators



Technology

Advanced Packaging Leadership
Engineering Services
Broad Portfolio



Quality

QualityFIRST Culture
Execution
Automation



Service

Design & Test Through Drop Ship
Manufacturing Footprint
Local Sales & Support

SYNOPSYS[®]

Silicon to Software[™]

COPYRIGHT NOTICE

This presentation in this publication was presented at the **Road to Chiplets: Architecture Workshop** (July 13 & 14, 2021). The content reflects the opinion of the author(s) and their respective companies. The inclusion of presentations in this publication does not constitute an endorsement by MEPTEC or the sponsors.

There is no copyright protection claimed by this publication. However, each presentation is the work of the authors and their respective companies and may contain copyrighted material. As such, it is strongly encouraged that any use reflect proper acknowledgement to the appropriate source. Any questions regarding the use of any materials presented should be directed to the author(s) or their companies.

www.meptec.org